Form 1449 (Modified) Information Disclosure	Atty Docket No. NOVLP075/NVLS-000820 Applicant:	Application No.: Unassigned	
Statement By Applicant (Use Several Sheets if Necessary)	Tipton et al. Filing Date HEREWITH	Group Unassigned	

U.S. Patent Documents

Examiner						Sub-	Filing
Initial	No.	Patent No.	Date	Patentee	Class	class	Date
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	A2	6,383,466	5/7/02	Domansky et al.	423	335	
	A3	6,365,266	4/2/02	MacDougall et al.	428	308.4	
	A4	5,504,042	4/2/96	Cho et al.	438	781	
	A5	5,858,457	1/12/96	Brinker et al.	477	162	
	A6	6,270,846	8/7/01	Brinker et al.	427	385.5	
	A7	6,387,453	5/14/02	Brinker et al.	927	387	
	A8	6,420,441	10/10/99	Allen et al.	521	77	
100	A9	6,271,273	10/10/00	You et al.	521	61.	

Foreign Patent or Published Foreign Patent Application

	Examiner			Publication	Country or		Sub-	Trans	lation
	Initial	No.	No.	Date	Patent Office	Class	class	Yes	No
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Other Documents

		Other Documents
Examiner		
Initial	No.	1
	Cl	Liu et al., "Mesoporous Silica Film From a Solution Containing a Surfactant
		and Methods of Making Same," U.S. Patent Application Publication No.
		US2002/0034626, Published March 21, 2002, 27 Pages
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(1		Surface Modification of Nanoporous Silica Films," U.S. Patent Application
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		2001, 13, No. 14, 1099-1102
	C5	Schulberg et al., "System for Deposition of Mesoporous Materials," U.S.
		Patent Application No. 10/295,965, filed November 15, 2002, 64 Pages
	C6	Watkins et al., "Mesoporous Materials and Methods," U.S. Patent Application
V	<u> </u>	No.10/301,013, filed November 21, 2002, 34 Pages

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9	C7	Justin F. Gaynor, "In-Situ Treatment of Low-K Films With a Silylating Agent After Exposure To Oxidizing Environments," U.S. Patent Application No.10/056,926 filed January 24, 2002, 34 Pages
6	C8	Gangpadhyay et al., "The First International Surface Cleaning Workshop," Northeastern University, November 11-14, 2002
Examiner I	YL	Date Considered 9/01/2004

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.